

» MOBILE» FLEXIBLE

» ADAPTABLE

» RAPID DEPLOYMENT



Give us a call or send us an email.

We will be happy to advise you. Reach your contact on:



+49 6400-9576030

Email

info@mk-versuchsanlagen.de

www.mk-versuchsanlagen.de

MK Versuchsanlagen und Laborbedarf e.K. Stueckweg 10 • D - 35325 Muecke-Merlau



METAL-FREE CLEANROOM TECHNOLOGY





METAL-FREE CLEANROOM TECHNOLOGY to meet your individual requirements



WETBENCH

- An ideal solution for use in the semiconductor industry
- Cleaning of substrates and equipment
- Non corrosive wet chemical etching (laminar flow)
- HEPA filter directly on the working chamber



WORK STATION VERTICAL

- · Cleaning of lab glass
- Avoidance of cross contamination
- Preparing samples for mass spectroscopic analyses
- Laminar flow
- HEPA filter directly on the working chamber



ISOLATOR VERTICAL

- RABS (Restricted Access Barrier System)
- Tight-closing
- Glove ports
- Connecting link through pass-through
- HEPA filter directly on the working chamber



COMBINATION STATION VERTICAL

- Processing and evaporation of samples
- Two different chambers in one station
- Laminar flow
- HEPA filter directly on the working chamber



EXHAUST VERTICAL

- Metal-free fume hood
- Avoidance of corrosion and cross contamination
- Etching processes
- No laminar flow, only exhaust



WORK STATION HORIZONTAL

- Processing and evaporation of samples
- Horizontal air flow
- Position of the hotplates can be changed as needed.
- HEPA filter directly on the working chamber